





XRF topography information simulations and data from a novel SDD system

• XRF is one of the most widely used non-destructive techniques for elemental analysis



- Novel multi-element silicon drift detector for low energy XRF
- 4 trapezoidal SDD arrays with 8 elements each

- XRF emission is an isotropic phenomenon
- Artefacts remain an issue with micro- or nano-X-ray beams
- The angular dependence may be an advantage in some cases
- The sample topography and surface roughness play an important role and may cause misleading interpretation if not carefully evaluated.



- It allows for a very large solid angle
 - Data acquired at the **TwinMic** beamline of Elettra Sincrotrone Trieste
- Detectors were tilted by 45°
- Total collection solid angle results in 0.54π steradians
- 27% of the hemisphere on which the sample emits XRF
- 7 times higher than previous setup







"bolder border"

- There is clear indication of shadows
- Evident angular dependence
 - XRF signal is stronger on the borders
 - The borders are illuminated more since they are in angle Risk for misinterpretations Shadows, Borders and Flat areas need to be normalised 3D topography can be revealed with the right model Different for each elements
- Impacts almost every XRF scan
- The detector type and geometry is important
 The new detector system can yield topographic information



Experimental and References

This work presents the latest findings of an ongoing research project on this topic [1]. It presents a simulation framework and the results of a new detector system based on 4 trapezoid sensors, each containing 8 SDD elements [2]. This new XRF system has been tested and optimized on the **TwinMic** beamline (Elettra Sincrotrone Trieste) [3].

[1] F. Billè et al., Spectrochimica Acta B, vol. 122, 2016
[2] J. Bufon et al., Journal of Instrumentation, vol. 13-03, 2018
[3] A. Gianoncelli et al., Synchrotron Radiation, vol. 23, 2016





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